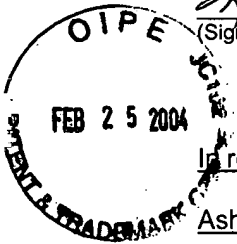


I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to : Commissioner of Patents and Trademarks, p. o. Box 1450, ALEXANDRIA, VA 22313-1450, on February 23, 2004. The applicant and/or attorney requests the date of deposit as the filing date.

Depositor: Karen Cing-Mars


Karen Cing-Mars 2/23/04
(Signature & date)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of _____: February 23, 2004

Ashima Chakravarti, et al. : Group Art Unit: Not yet assigned

Serial No. 10/707,878 : Examiner: Not yet assigned

Filed: 1/20/04 : International Business Machines Corporation
2070 Route 52
Hopewell Junction, NY 12533

TITLE: Polycrystalline Silicon Layer With Nano-Grain Structure And Method of Manufacture

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

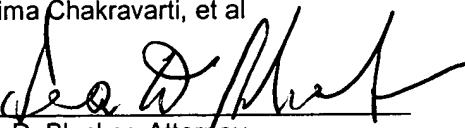
Sir:

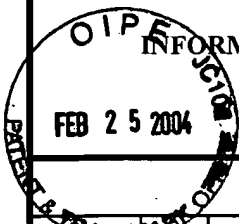
Pursuant to the duty of disclosure set forth in 37 C.F.R. 1.56, and further pursuant to the provisions of 37 C.F.R. 1.97 and 1.98, applicants hereby respectfully submit copies of the non-US patents and publications as listed on Form PTO-1449, attached hereto.

In citing these documents, no representation is made nor intended as to the pertinency or non-pertinency of the art, that better art than that listed is not available, or that other art is not applicable.

No fee is believed to be due for this submission. If any fees are required, however, the Commissioner is hereby authorized to charge such fees to Deposit Account No. 09-0458.

Respectfully submitted,
Ashima Chakravarti, et al

By 
Ira D. Blecker, Attorney
Registration No. 29,894
Telephone No. 845-894-2580



INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

Docket Number (Optional)

fis920030317us1

Application Number

10/707,878

Applicant(s)

Ashima Chakravarti, et al.

Filing Date

1/20/04

Group Art Unit

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

		Silicon Processing for the VLSI Era, S. WOLF and R. N. TAUBER, Lattice Press, Sunset Beach CA, USA 1986 - Pgs. 179 - 181.

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.